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**DESCRIPTION OF DRAWINGS**

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[Brief Description of the Drawings]

[Drawing 1] It is a perspective view showing the simulated defect sample of this invention, and the laser marking device which records a simulated defect.

[Drawing 2] It is a schematic diagram showing a defect inspection device.

[Drawing 3] It is a front view showing the simulated defect sample arranged to the scanning position.

[Drawing 4] It is an explanatory view showing the diffusion degree of the optical beam in the simulated defect of this invention.

[Drawing 5] It is an explanatory view showing the diffusion degree of the laser beam at the time of making the scanning direction of a laser beam, and a simulated defect cross at right angles, and constituting it.

[Drawing 6] It is a front view showing the simulated defect sample which has a simulated defect of several different classification.

[Drawing 7] It is a front view in which changing an angle of gradient into for the same simulated defect, and showing the poor simulated defect sample about the same as plurality.

[Drawing 8] It is a front view in which changing an angle of gradient into for the simulated defect of a different classification, and showing the poor simulated defect sample about the same as plurality.

[Description of Notations]

10, 65, 70, and 80 Simulated defect sample

12 Laser marking device

13, 60-64, 71-74, 75-78 Simulated defect

20 Defect inspection device

30 Photodetector

31 Mask

32 Sensor window

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[Translation done.]